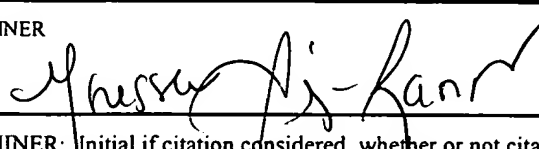


PTO-1449 Information Disclosure Citation in an Application			Application No. TBD 09/732468		Applicant(s) Christopher M. Bowles, et al.		
Docket Number TI-24521			Group Art Unit TBD		Filing Date 12/07/00		

U.S. PATENT DOCUMENTS							
	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
A	5,536,675	07/16/96	Bohr	437	67	08/07/95	
B							
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FOREIGN PATENT DOCUMENTS								
	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION		
						YES	NO	
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NON-PATENT DOCUMENTS		
	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
S	A New Planarization Technique, using a Combination of RIE and Chemical Mechanical Polish (CMP) by B. Davari, et al.; <u>IEEE</u> © 1989, pp. 3.4.1 - 3.4.4	1989
T		
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EXAMINER 	DATE CONSIDERED 12/2/01
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.